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APPLICANTS

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\*\* CONTINUING DATA \*\*\*\*\*  
*SRM NONE*

\*\* FOREIGN APPLICATIONS \*\*\*\*\*  
 JAPAN P2002-189086 06/28/2002  
*SRM*

IF REQUIRED, FOREIGN FILING LICENSE GRANTED  
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Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY JAPAN	SHEETS DRAWING 4	TOTAL CLAIMS 20	INDEPENDENT CLAIMS 3
35 USC 119 (a-d) conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance	Examiner's Signature <i>SRM</i>	Initials <i>SRM</i>		
Verified and Acknowledged				

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TITLE

Exposure method, mask fabrication method, fabrication method of semiconductor device, and exposure apparatus

FILING FEE  RECEIVED 750	FEES: Authority has been given in Paper. No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:	<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees ( Filing ) <input type="checkbox"/> 1.17 Fees ( Processing Ext. of time ) <input type="checkbox"/> 1.18 Fees ( Issue )
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